



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 9191**  
Makoto AKIZUKI et al. : **Docket No. 2001-1897**  
Serial No. 10/025,899 : **Group Art Unit 1762**  
Filed December 26, 2001 : **Examiner B. Pianalto**

METHOD FOR FORMING GAS CLUSTER AND  
METHOD FOR FORMING THIN FILM

**PETITION FOR EXTENSION OF TIME**

Assistant Commissioner for Patents,  
Washington, DC 20231

THE COMMISSIONER IS AUTHORIZED TO  
FORGIVE ANY DEFICIENCY  
IN THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0975

Sir:

Petition hereby is made for a three month extension of time to respond to the communication of  
August 7, 2002.

The fee of \$930.00 is

- (X) submitted herewith.  
( ) to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is  
enclosed.  
( ) Small entity status of this application is established by a Small Entity Status Assertion  
which  
( ) is enclosed.  
( ) has been previously submitted.

Respectfully submitted,

Makoto AKIZUKI et al.

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